Appl. No. 10/702,442

Amendment dated: August 25, 2006

Reply to OA of: May 15, 2006

This listing of claims will replace all prior versions and listings of claims in the application.

Listing of Claims:

1(currently amended). A method of treating a surface of a substrate, said method comprising the following steps of:

- (a) forming bubbles with a liquid and a gas on the surface of the substrate comprising immersing a plurality of the substrates which are equidistantly arranged and are parallel to one another in the liquid contained in a bath such that only bottom portions of the substrates are immersed in the liquid, and the gas is introduced to the bath to form the bubbles; and
- (b) allowing the gas bubbles to ascend along the surface of the substrate, including the surface above the horizon of the liquid, such that the gas bubbles work to strip a substance from the surface of the substrate, or that the gas bubbles work to form a substance on the surface of the substrate;

wherein the liquid comprises ozone water, the gas comprises a gas mixture comprising ozone, and the substance comprises a photoresist.

2(canceled).

3(previously presented). The method as defined in claim 2, wherein the substrate is a wafer.

Claim 4(canceled).

5(previously presented). The method as defined in claim 1, wherein the substrate is vertically immersed in the liquid contained in the bath, and the substrate

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is driven to turn in the bath, thereby enabling outer edges of the substrate to be immersed in the liquid in rotation.

Claim 6-9(canceled).